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Attorney Docket: 061063-0316598  
Client Reference: OSP-18418

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of: PARK ET  
AL.  
Application No.:

Confirmation Number:

Group Art Unit:

Filed: June 28, 2005

Examiner:

Title: CHEMICAL-MECHANICAL-POLISHING SLURRY COMPOSITION, METHOD  
FOR PLANARIZING SURFACE OF SEMICONDUCTOR DEVICE USING THE SAME,  
AND METHOD FOR CONTROLLING SELECTION RATIO OF SLURRY COMPOSITION

PRELIMINARY AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Before beginning examination, please amend the above-identified application as  
follows: